



WIR SCHAFFEN WISSEN – HEUTE FÜR MORGEN

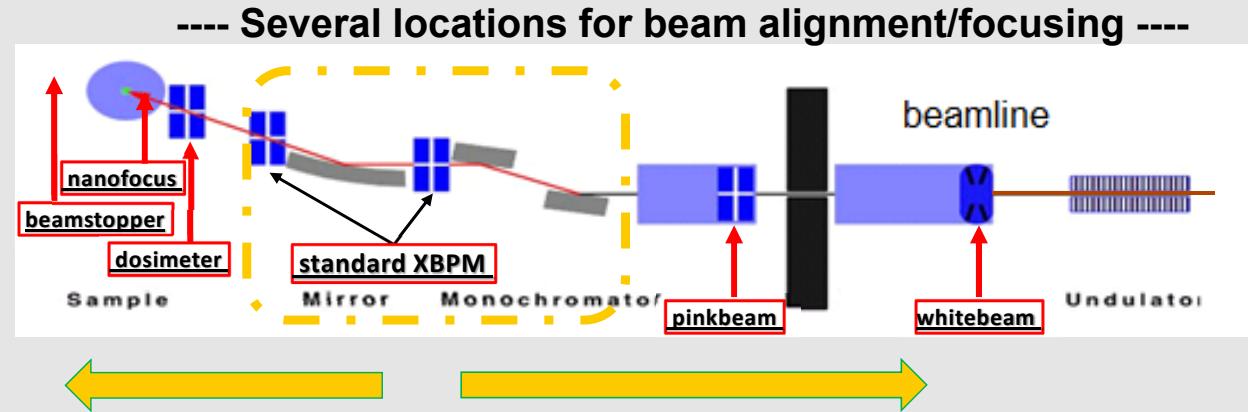
Towards full Silicon Carbide based beam monitoring

Mar Carulla

Outline

- Overview of beam monitors at SLS
 - Advantages and drawbacks
- State-of-art on solid state monitors for hard Xray
 - SiC vs. Diamond
- Wafer scale processing of SiC XBPM
 - SiC XBPMs produced on 4 inch. wafers
- Current Installations
 - microSAX: After mono, beam stopper and I_0
 - PXI: Pinkbeam
- Future installations
 - nano-imaging
- Extension towards soft-, pink- and white-beams
- Conclusions and outlook

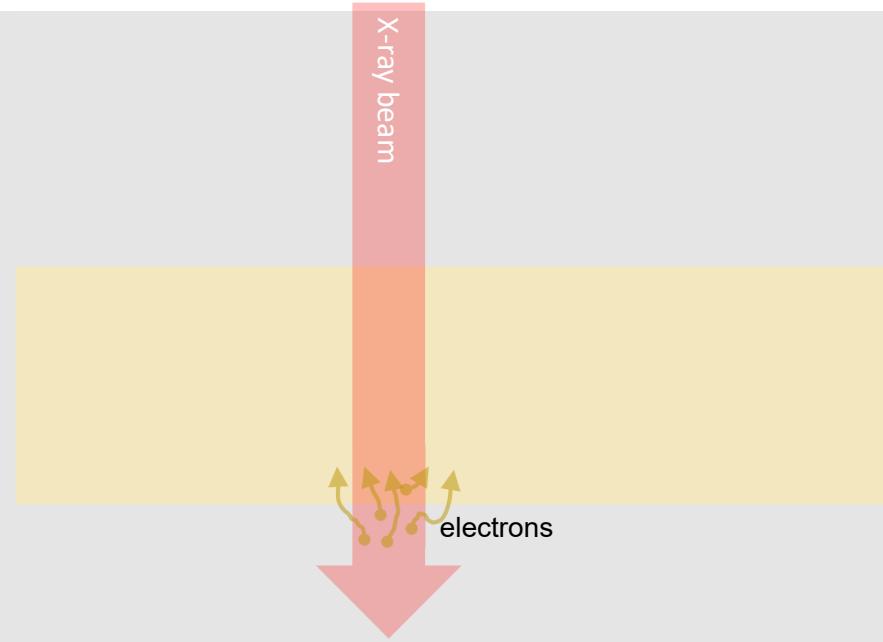
Overview XBPM



Requirements for in-line X-ray beam monitors

1. Transparency (<2%)
2. Stability over time, i.e. radiation hardness
3. Uniformity (transmittance and photocurrent)
4. Fast response (μs)
5. Easy of fabrication/ Easy of usage / low footprint / vacuum compatibility

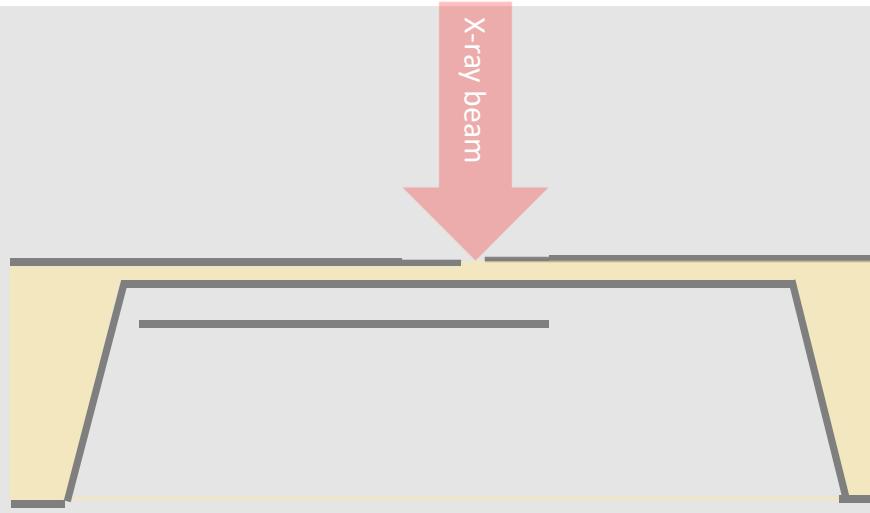
Solid state XBPMs



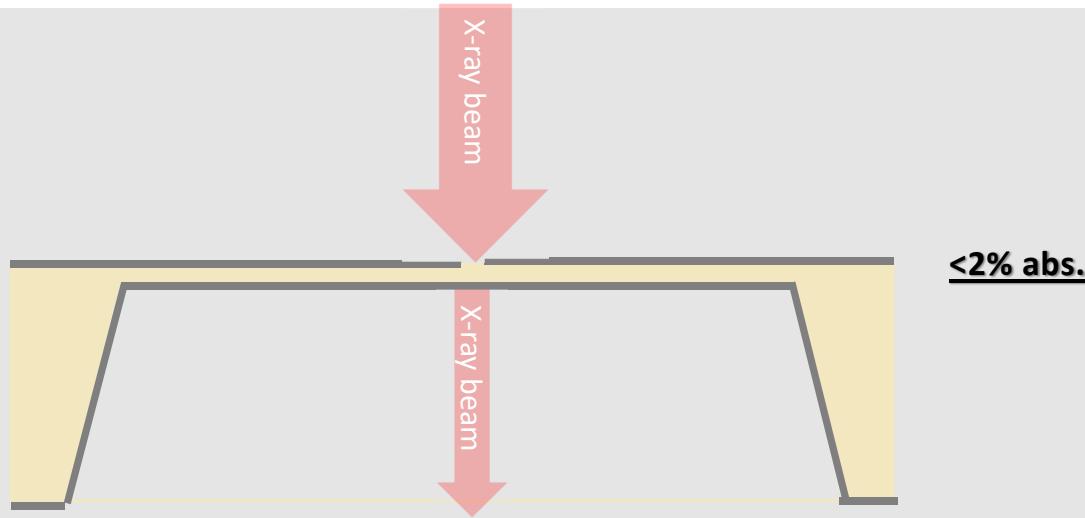
Solid state XBPMs



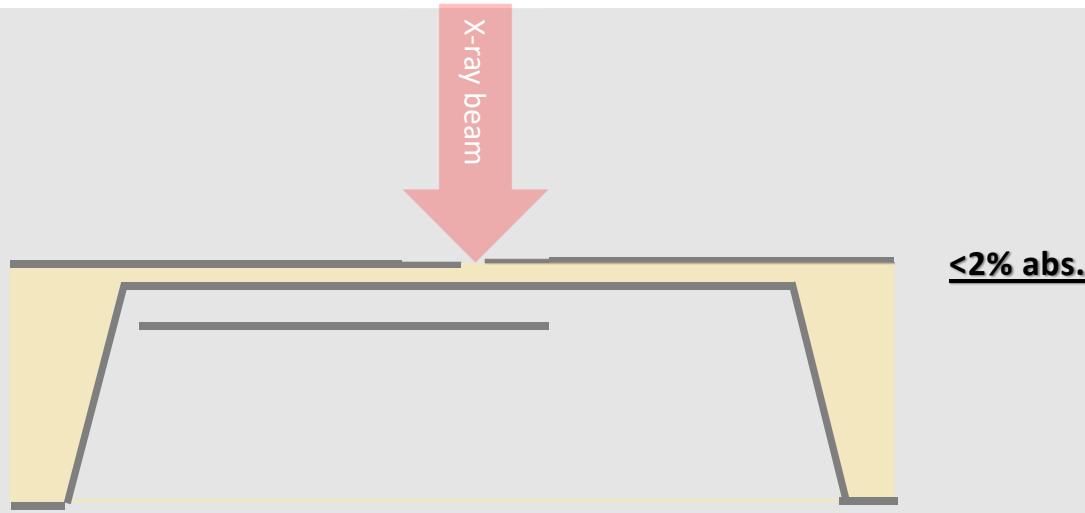
Solid state XBPMs



Solid state XBPMs



Solid state XBPMs

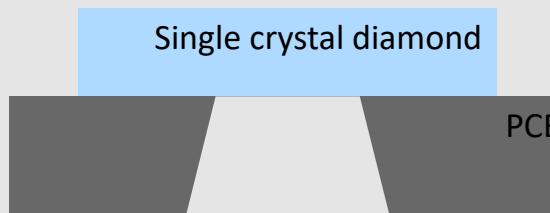


Solid state XBPMs



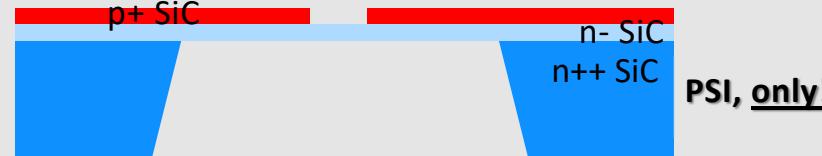
**DECTRIS, RIGI
SYDOR**

**Limited in quality
Poor time response**



**CIVIDEC
SYDOR**

**Limited in thickness
Limited in size**

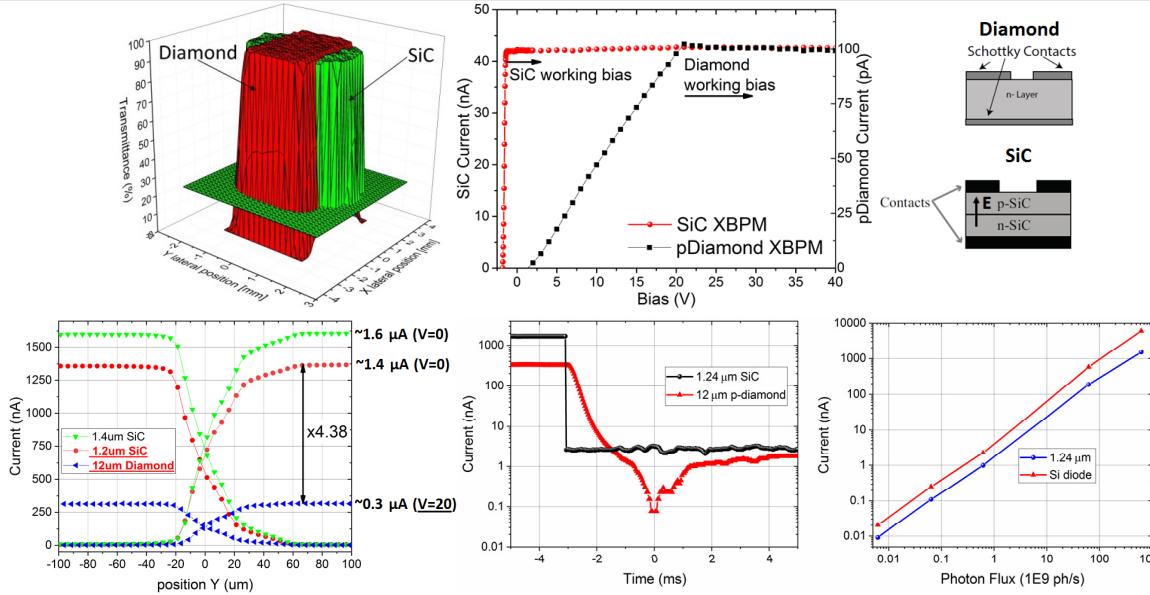


PSI, only!

**up to 4-8 inch
down to 1um (0.1)
multiple level mems.**

Solid state XBPMs

Comparison with polycrystalline diamond



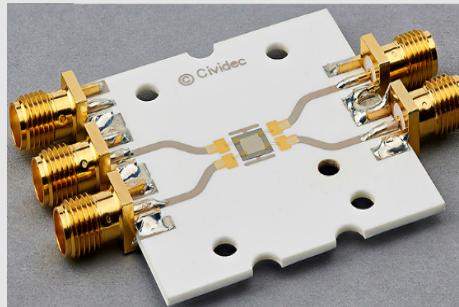
- SiC XBPM clearly superior to "RIGI" polycrystalline XBPM.
- RIGI now out of the market (No other polycrystalline XBPM vendors)

*Nida S. et al "Silicon carbide X-ray beam position monitors for synchrotron applications": J. Synchrotron Rad. 2019, 26, 28-35
<https://doi.org/10.1107/S1600577518014248>

Solid state XBPMs

Comparison with single crystalline diamond

single crystal Diamond



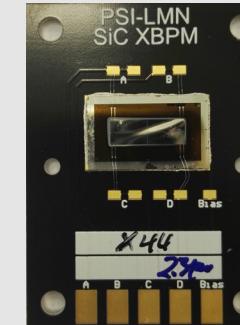
8 order linearity

~ns response

20 μm min. thickness

7 mm^2 Active Area

SiC XBPM



4 order magnitude linearity*

~ μs response*

2 μm min. thickness

36 mm^2 (72 mm^2) Active Area (x5)

* limited by measurement setup

** considering different att. length

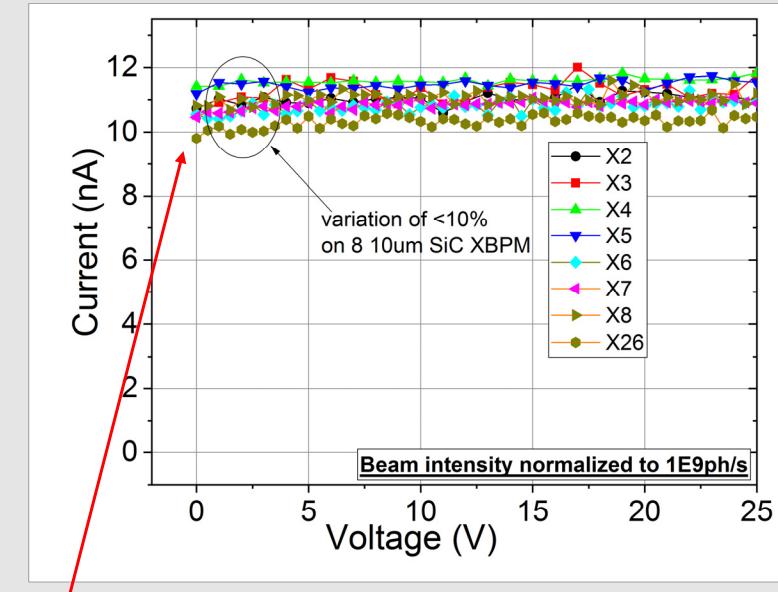
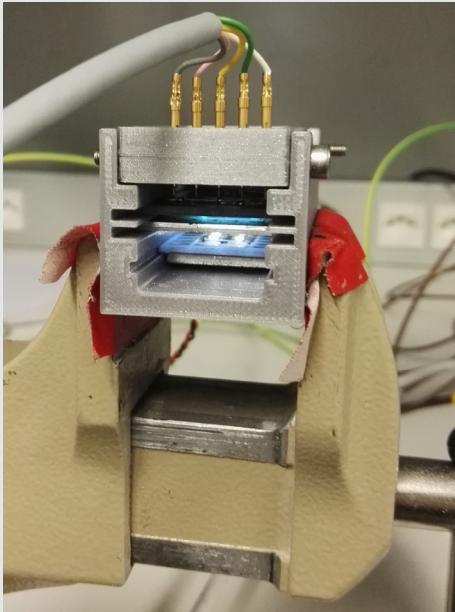
Wafer scale processing



- **50 devices per wafer**
- **Wafer processing lasts 2 weeks**

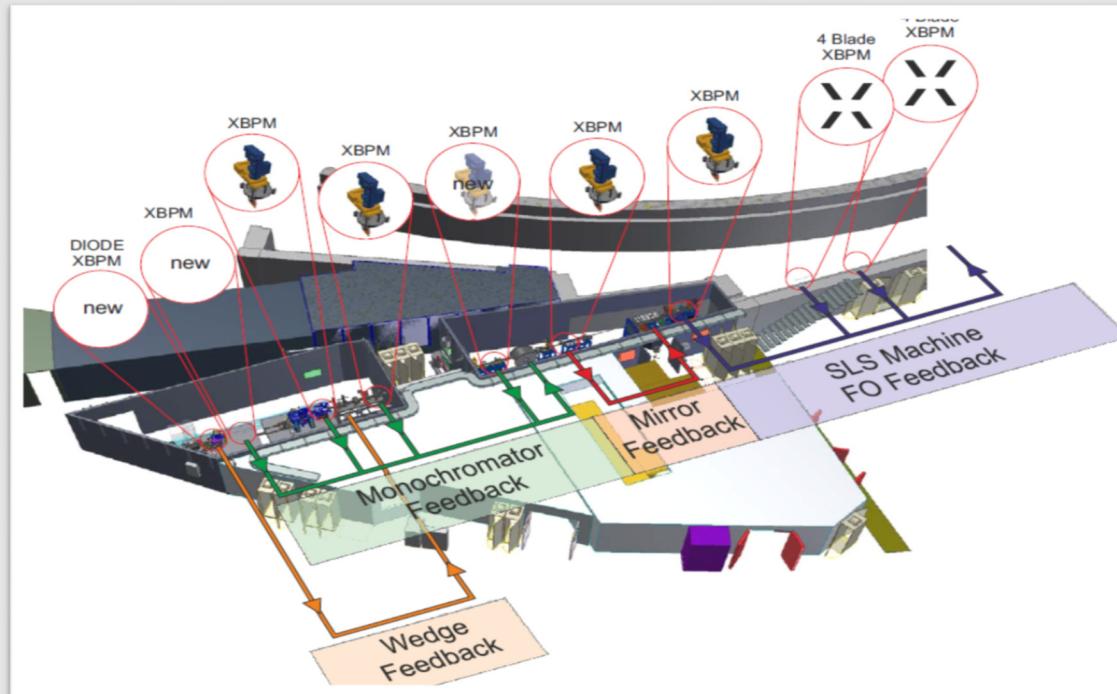
Wafer scale processing of SiC Stability

- Fully automated UV (325nm) LED based screening system



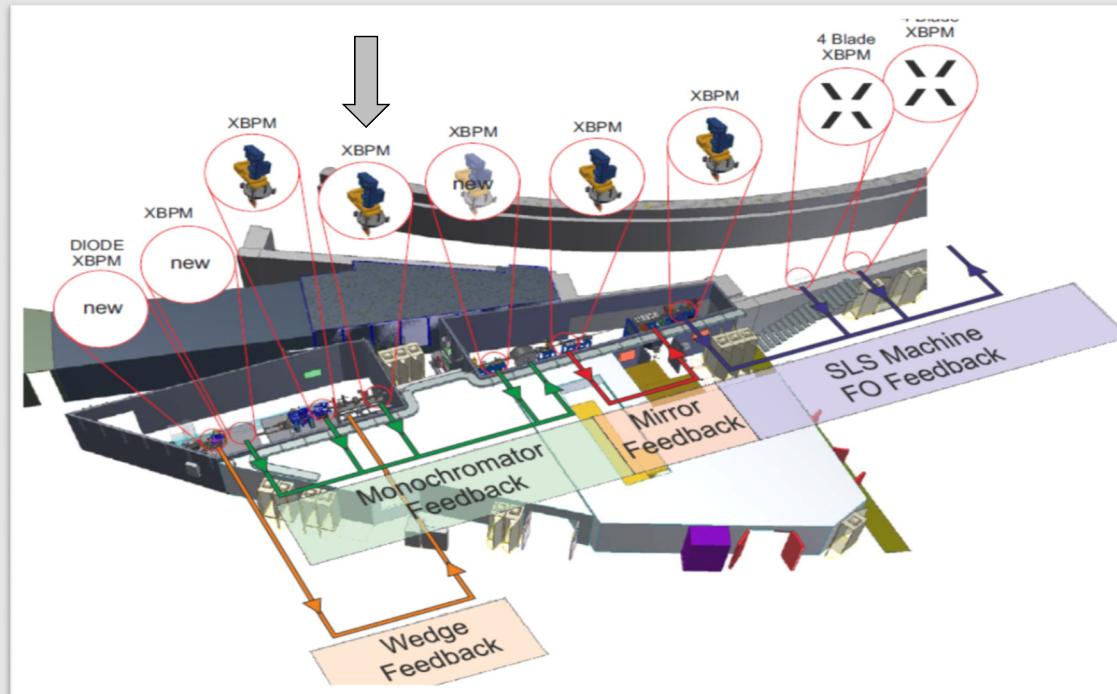
Operation at 0V

Current installations at microXAS



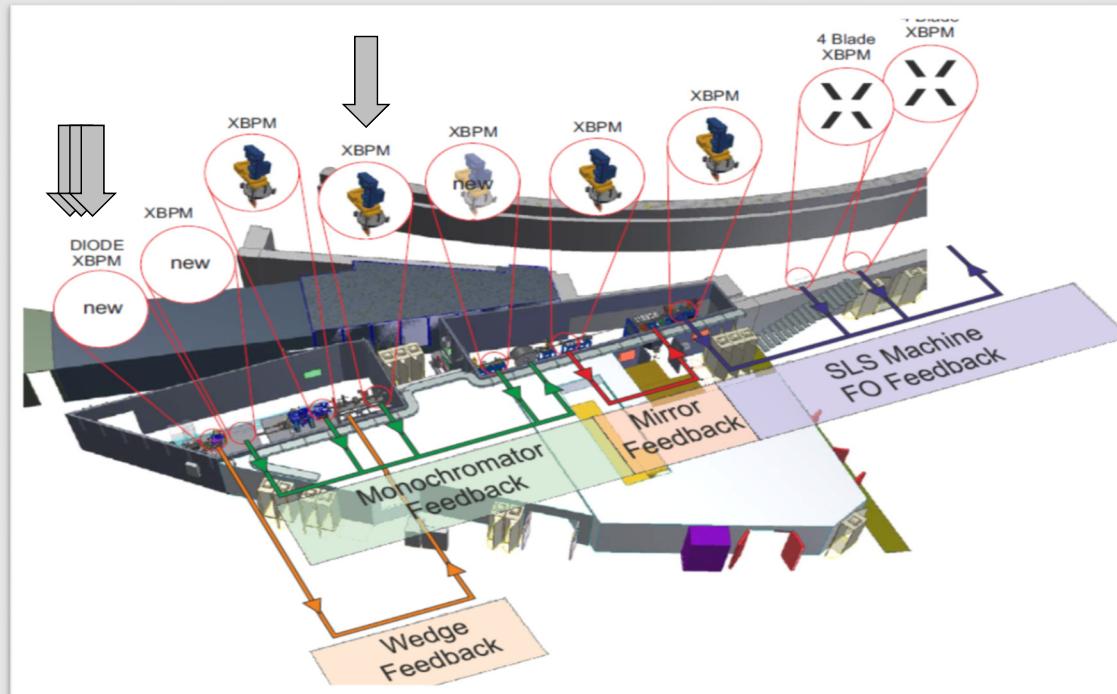
- Currently installed @ microXAS: 3 XBPMs (after mono, IO, and beam-stopper)

Current installations at microXAS



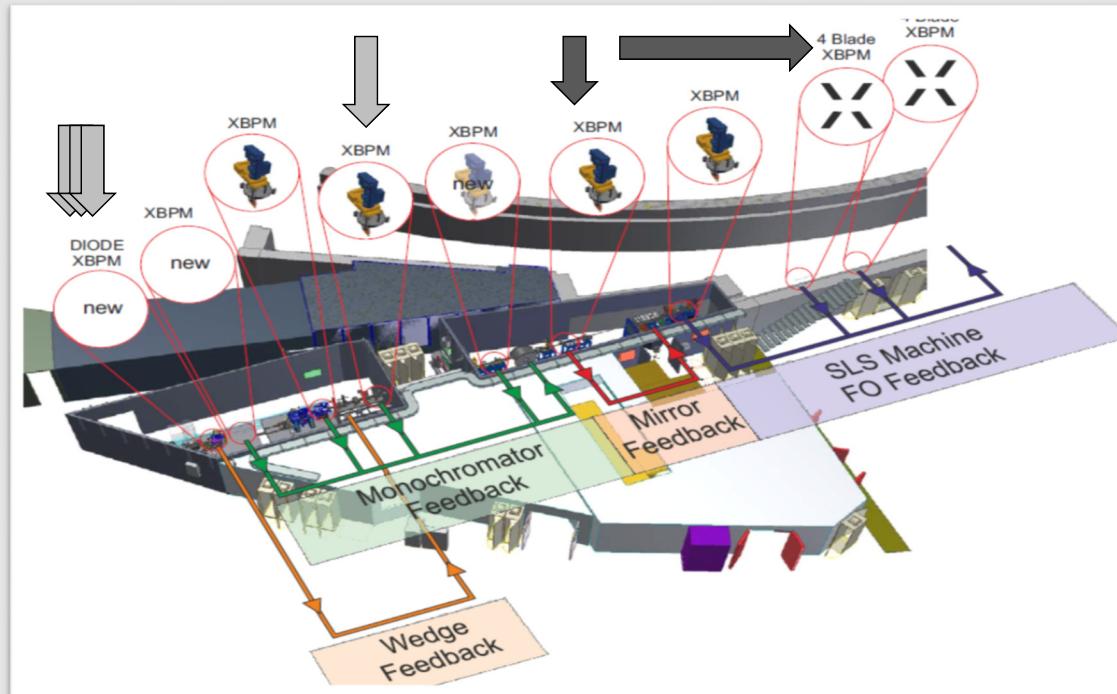
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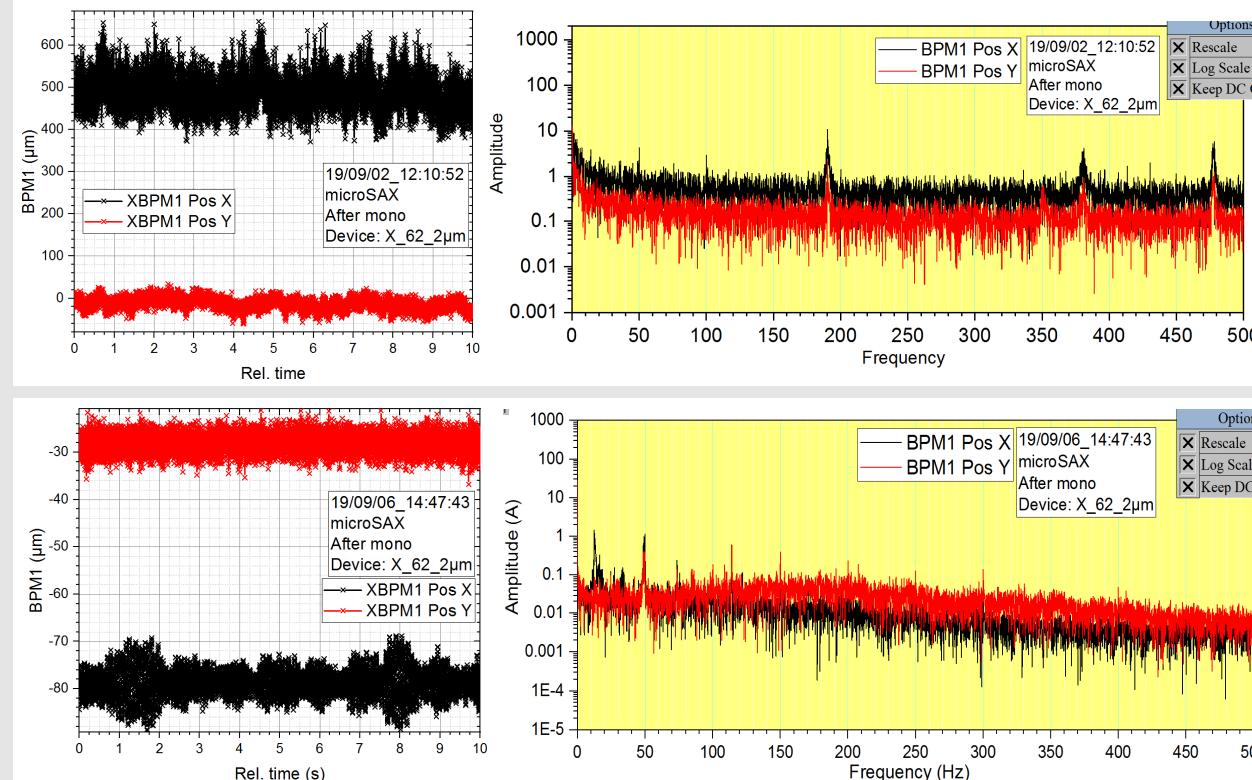
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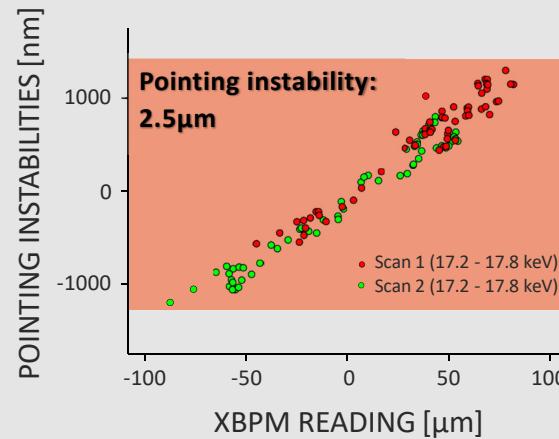
Current installations at microXAS

-first implemented SiC XBPM

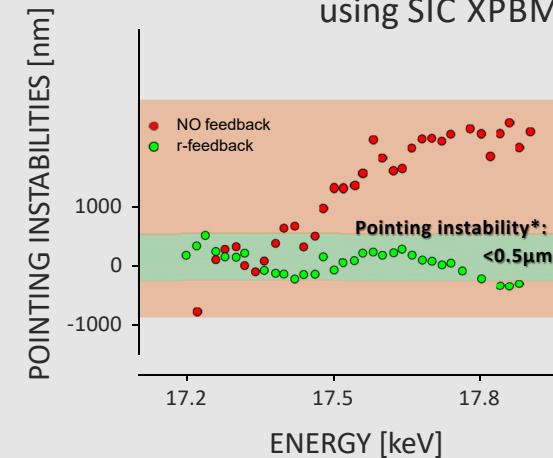


Current installations at microXAS

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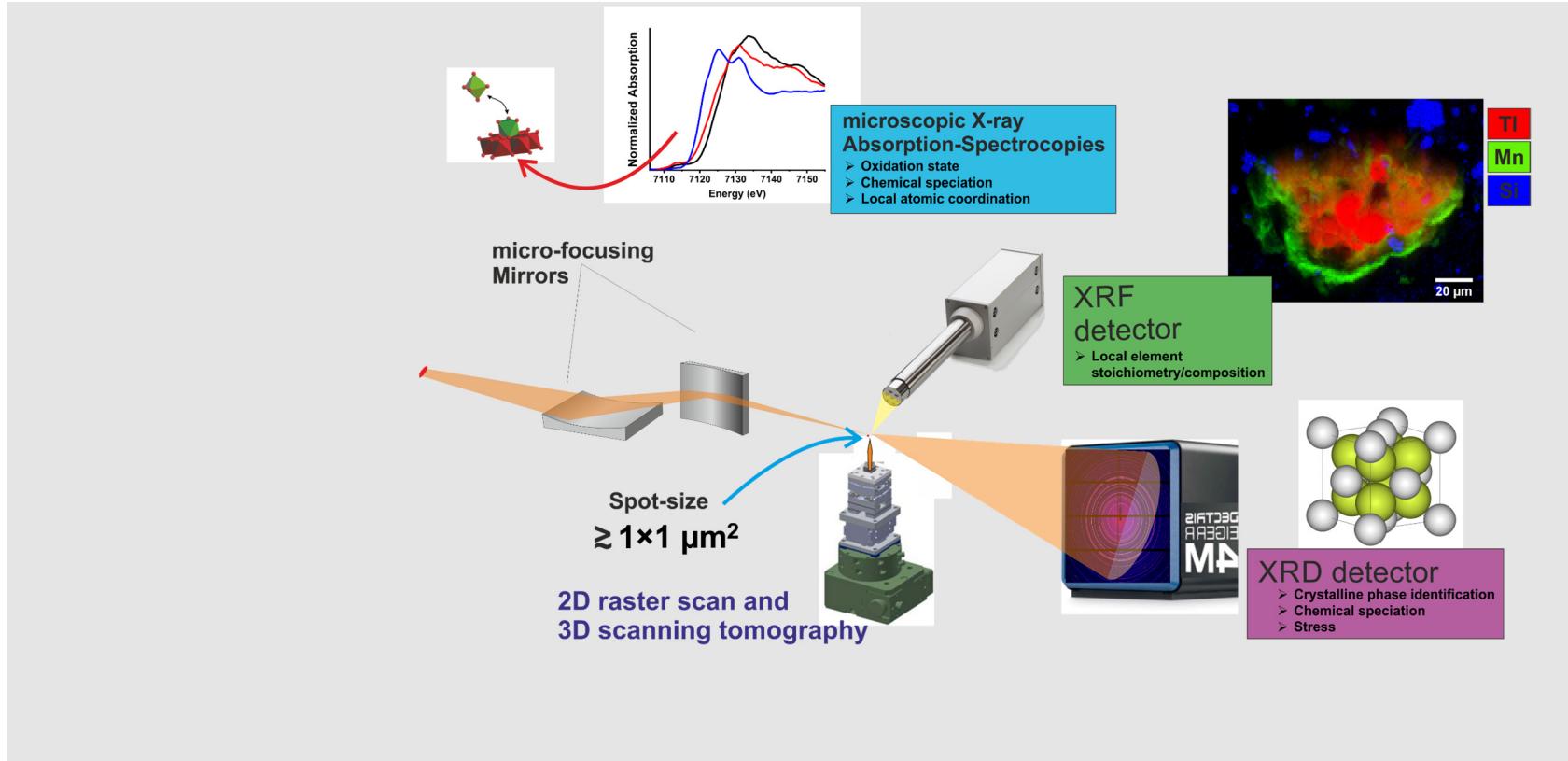
Improvement based on
rudimentary feedback system
using SiC XPBM



*sigma: <400nm

Current installations at microXAS

-Beam stopper diode (no transmittance mode)



Current installations at microXAS

-Beam stopper diode (no transmittance mode)

Absorption → SiC Diode on the beamstopper

- Absorption Contrast Imaging
- X-Ray Absorption Spectroscopy

Collaboration of microXAS team with Massimo Camarda,
Laboratory for Micro- and Nanotechnology, PSI

- 3D Mechatronic Integrated Device

Normalized Absorption
Energy (eV)

microscopic X-ray Absorption-Spectroscopies

- Oxidation state
- Chemical speciation
- Local atomic coordination

micro-focusing Mirrors

Spot-size $\gtrsim 1 \times 1 \mu\text{m}^2$

2D raster scan and 3D scanning tomography

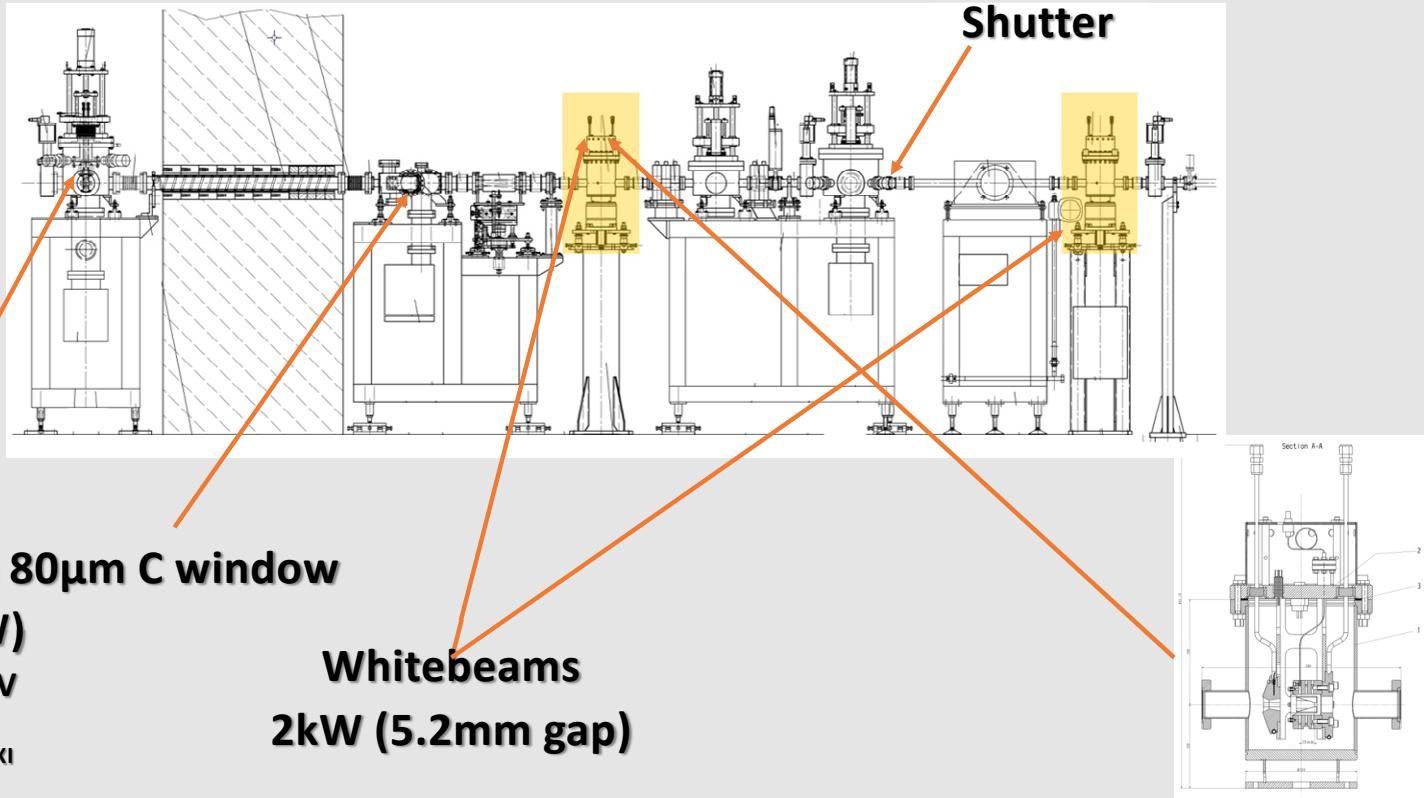
XRF detector
➤ Local element stoichiometry/composition

XRD detector
➤ Crystalline phase identification
➤ Chemical speciation
➤ Stress

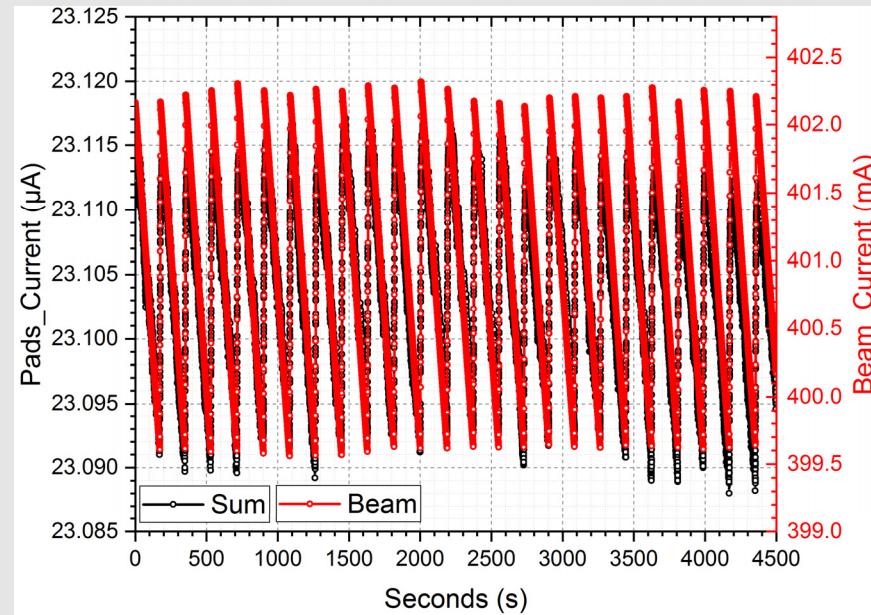
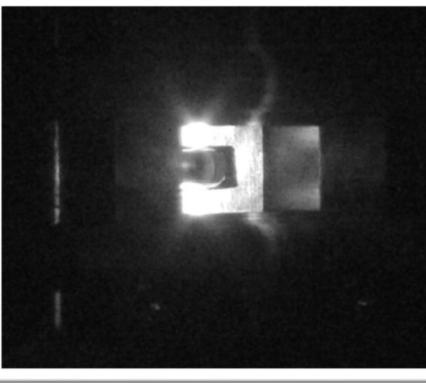
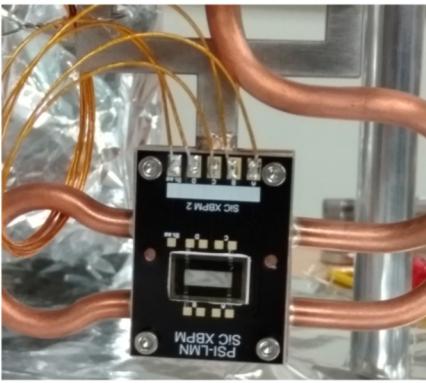
Element Map
TI (Red), Mn (Green), Si (Blue)
20 μm

Courtesy: Dario Sanchez

Current installations at PXI (pinkbeam)

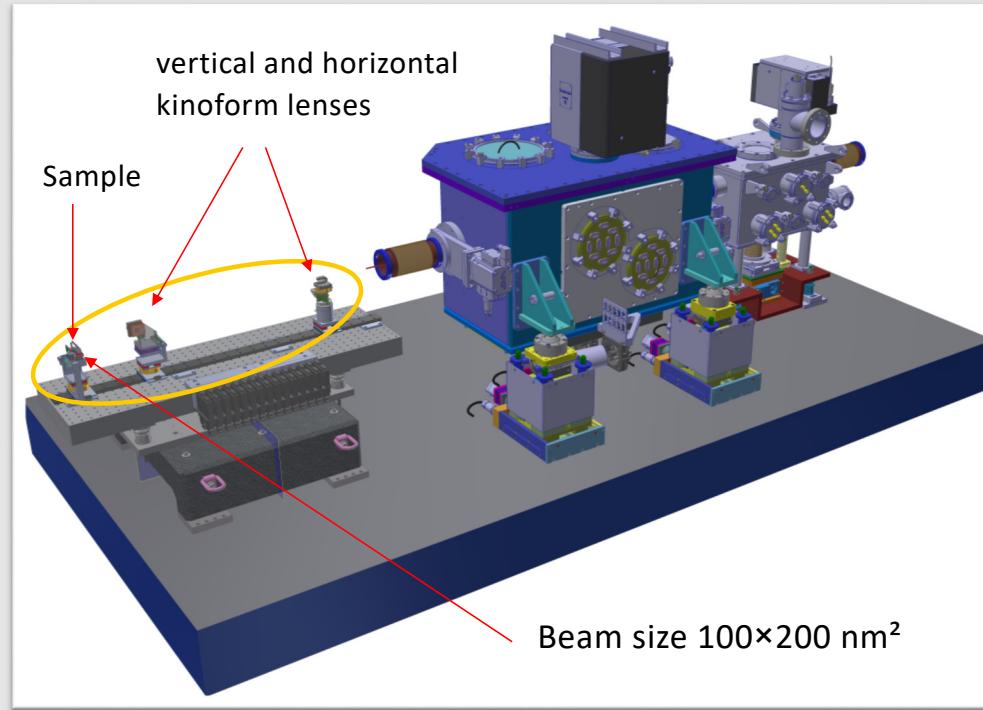


Current installations at PXI (pinkbeam)

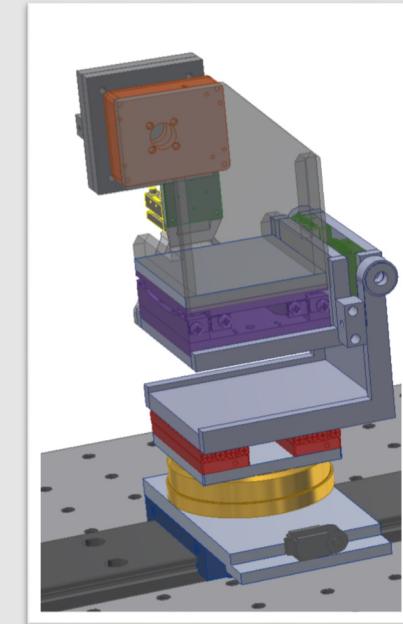


- 2 μm XBPM was installed 1 month ago at PXI pinkbeam (after diamond window).
- The measured current is several order of magnitude lower than the expected one.

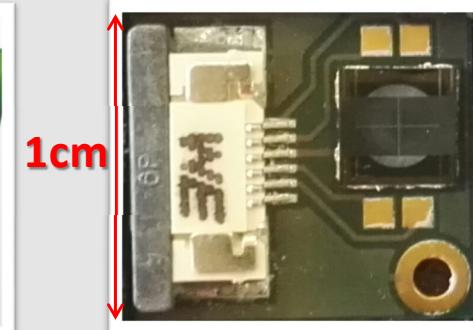
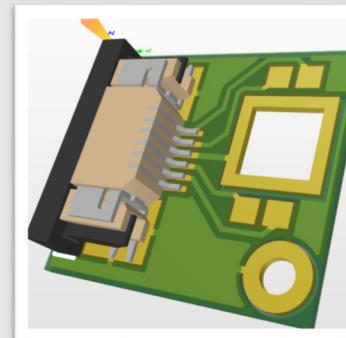
Future installations: Near sample monitoring -3 compact XBPM for nano-imaging



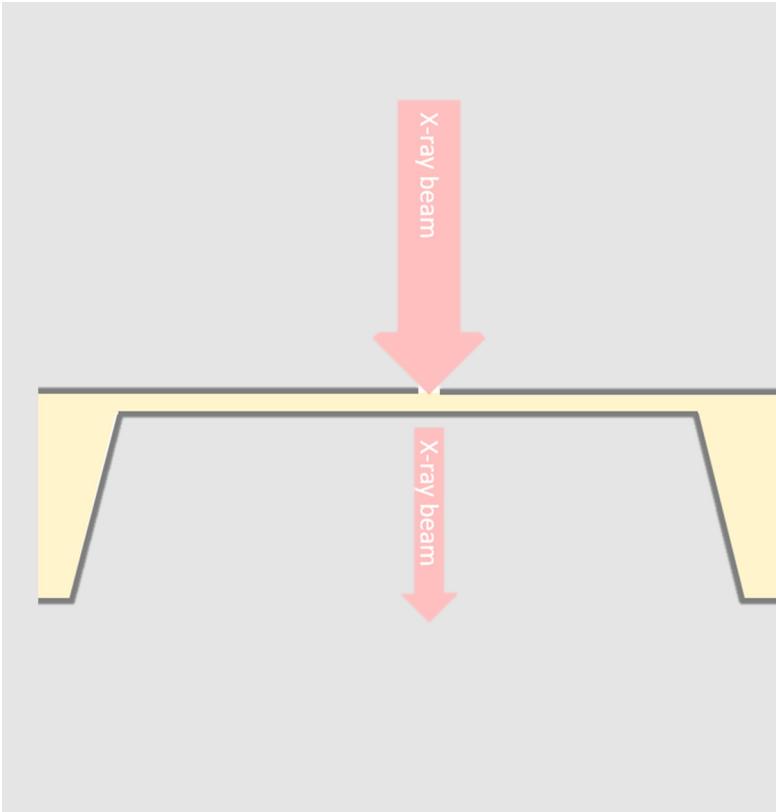
Future installations: Near sample monitoring -3 compact XBPM for nano-imaging



Installation expected
Dec. – Nov. this year

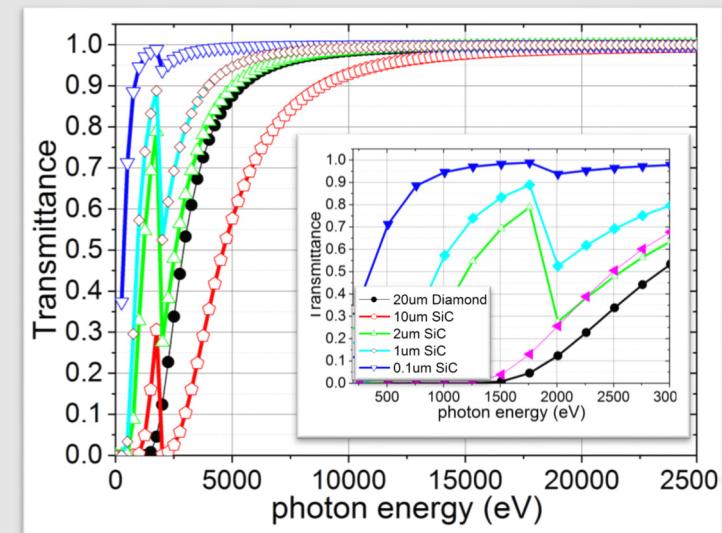


Future extensions: soft/pink/white x-ray beams

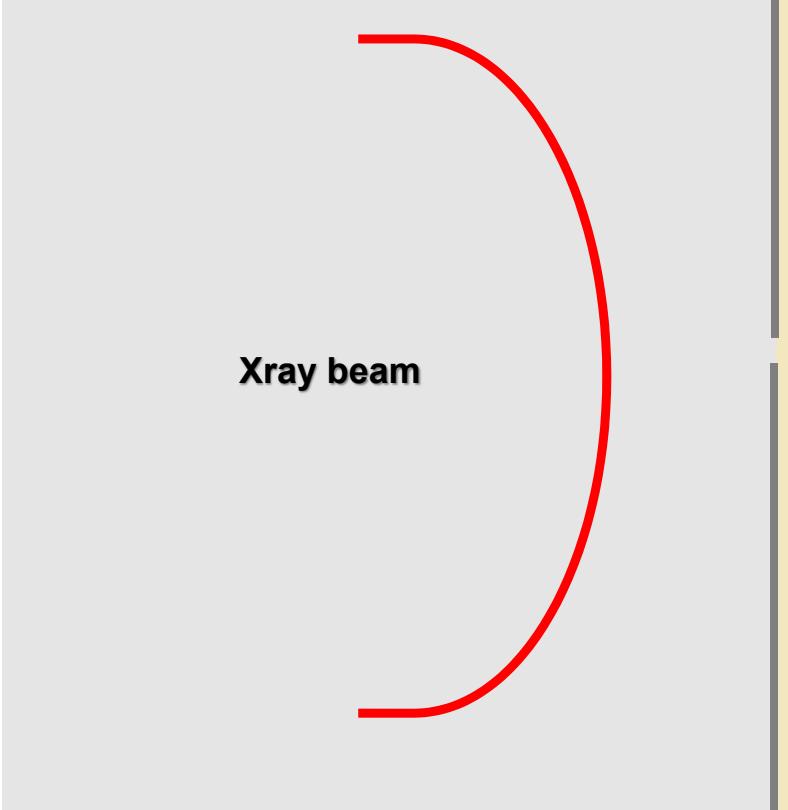


Limitation of thin membranes as XBPM:

- 1) high abs. for soft x-ray
- 2) thermal issues for white beams

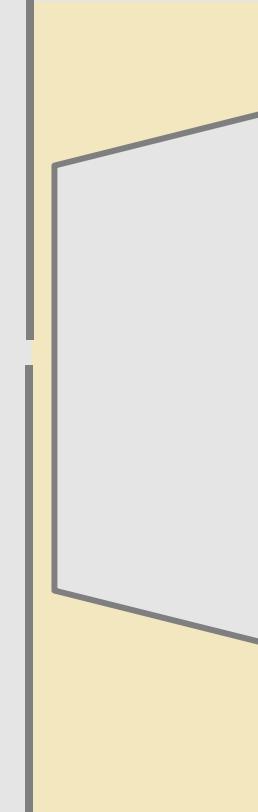


Future extensions: white x-ray beams



Xray beam

The diagram shows a red, curved line representing an X-ray beam path. The beam starts at the bottom left, moves upwards and to the right, then turns sharply downwards and to the right, forming a large arc. The background is light gray.



Future extensions: white x-ray beams

Xray beam

=0% abs.

Future extensions: white x-ray beams

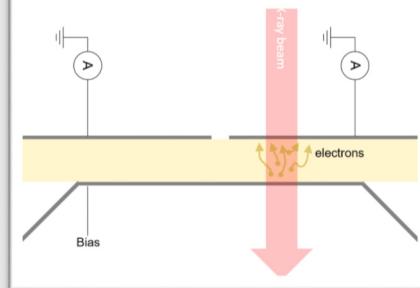


Future extensions:

Why better than blades

Why valuable "functionalized" pin-holes

semiconductor based
internal photoemission

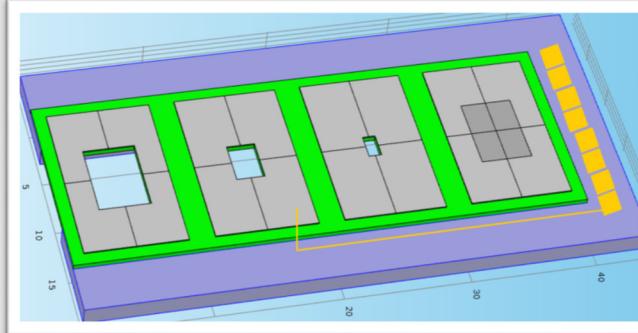
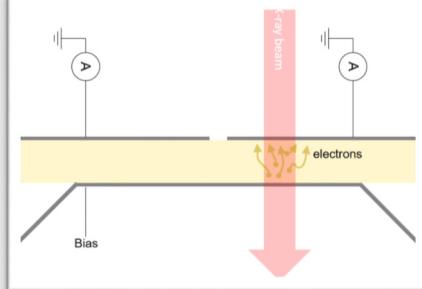


Future extensions:

Why better than blades

Why valuable "functionalized" pin-holes

semiconductor based *internal* photoemission



array of 4 devices

1. -- full membrane, -- "high res."
 2. --"small pin-hole": 2.0x1.0mm²
 3. --"blade opening": 3.4x2.2mm²
 4. --"large pin-hole": 6.0x4.0mm²

Conclusions and outlook

Conclusions:

- 4H-SiC XBPM: transparency, linearity, signal strength.
- They can be operated at 0V.
- 2 μm 4H-SiC XBPM devices were installed at microSAX (after monochromator) and PXI (pinkbeam) beamlines at PSI.
- PXI (pinkbeam): current several orders of magnitude lower than expected.
- microSAX (after monochromotar): 20 \times improvement on beam stability over energy scans

Future work:

- Installation of Compact XBPMs for nano-imaging
- Blade monitors (whitebeam)
- 0.1 μm thin XBPM for soft X-rays

Acknowledgments

- Hans Sigg
- Oliver Bunk
- Claude Pradervand
- Daniel Grolimund
- Dario Sanchez
- Mario Birri
- Beat Meyer
- ALL LMN
- pBPM working group

